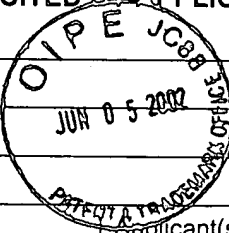
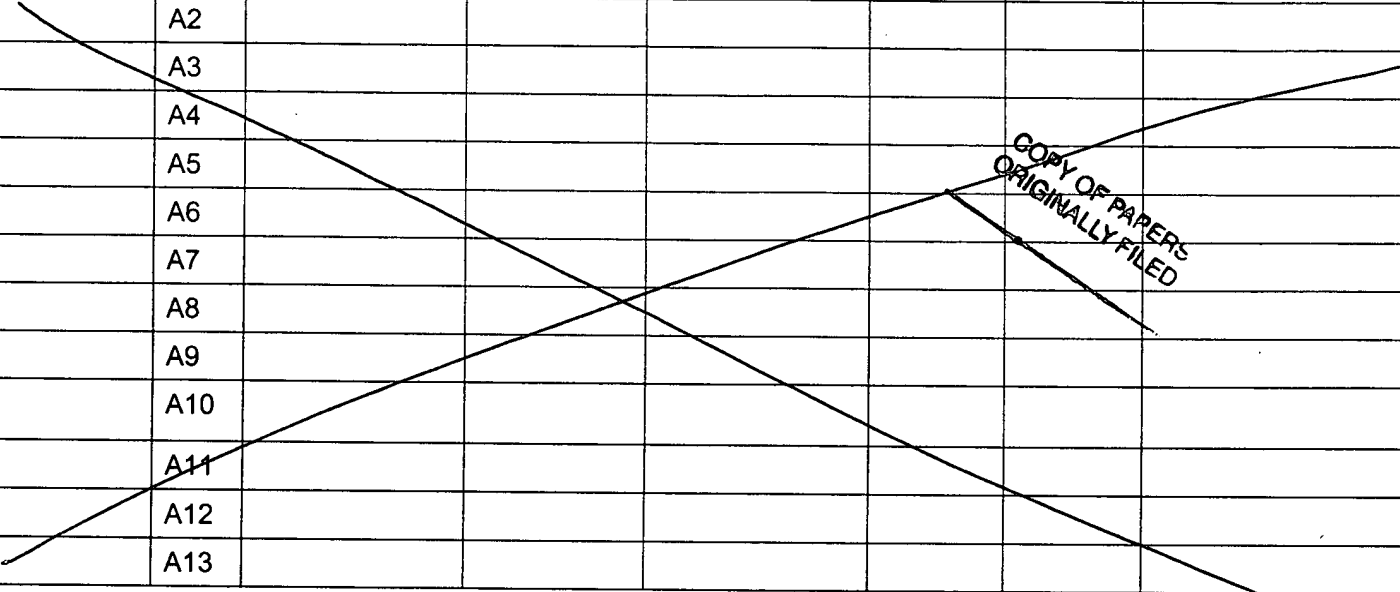



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| Examiner Unknown | | | | | | | |

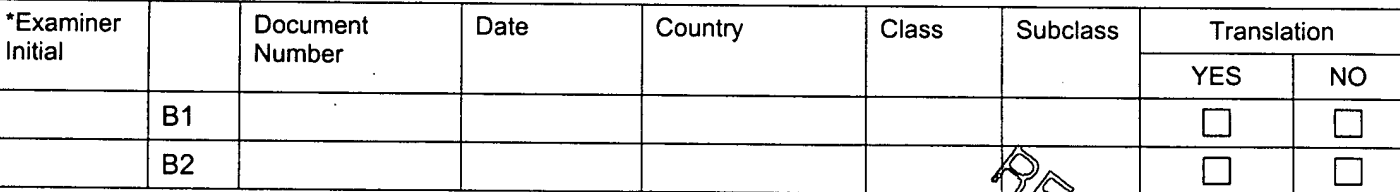


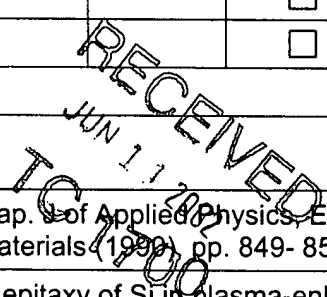
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| | B2 | | | | | <input type="checkbox"/> | <input type="checkbox"/> |





| *Examiner Initial | Including Author, Title, Date, Pertinent Pages, Etc. |
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